SEMICONDUCTOR PIEZOMETERS AND PRESSURE TRANSDUCERS





APPLICATIONS

For the measurement of:

- Ground water elevations
- Pore water pressure
- Pumping and slug tests
- Uplift pressures in dam foundations
- Hydraulic pressures in tanks and pipelines

- Wick drain efficiency
- Water pressure behind tunnel linings
- Aquifer storage and recovery
- Watershed, drainage basin and recharge areas
- Groundwater network automation

OPERATING PRINCIPLE

The 3400 Series Semiconductor Piezometers (3400S/SV) and Pressure Transducers (3400H) are intended for dynamic measurements of fluid or pore water pressure, or for static pressure measurements where the readout system or data acquisition system is incompatible with vibrating wire type transducers.

The transducers use molecularly bonded (CVD) high output strain gauges to provide 100 mV output for full pressure when used with a 10 VDC supply. The high output versions are fitted with an ASIC providing outputs

of 0–5 VDC or 4–20 mA, which are capable of being used in control and indicating loops without further amplification.

Piezometers incorporate a filter stone ahead of the diaphragm, which allows the fluid to pass through but prevents soil particles from impinging directly on the diaphragm. Standard porous filters are stainless steel. High air-entry ceramic filters are available for use in applications requiring that air be prevented from passing through the filter.



Model 3400SV-1/2 Semiconductor Vented Piezometer

ADVANTAGES AND LIMITATIONS

The transducer is made from 17-4 stainless steel and is housed in a rugged stainless steel housing guaranteeing a high level of corrosion resistance, and providing long term reliable measurements in all applications.

Signal cables are attached via proprietary bulkhead seals providing a high integrity, waterproof assembly.

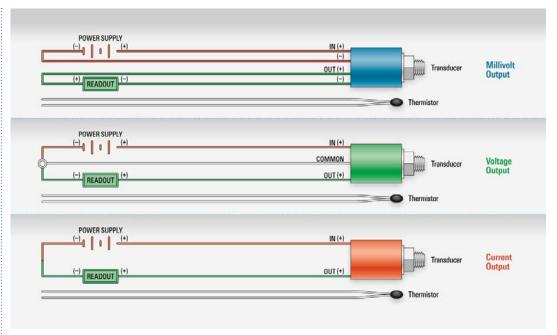
A variety of cable types are available to suit particular user applications.

Vented versions of all models are available to provide automatic compensation for barometric pressure fluctuations.

A thermistor located in the housing permits the simultaneous measurement of temperature at the piezometer location.



Model 3400H and Dial Gauge Pressure Transducer on a tee fitting.



Model 3400 Series Semiconductor Piezometer wiring schematics.

TECHNICAL SPECIFICATIONS	
Standard Ranges	100, 250, 400, 600 kPa; 1, 2.5, 6 MPa
Over Range	2 × rated pressure
Response Time	0.5 ms
Wetted Parts	(Transducer) 17–4 PH stainless steel
Output	10 mV/v, 4–20 mA, 0–5 V
Accuracy	<0.1% F.S. (dependent on readout)
Linearity	<0.5% F.S.
Shock	20 g, 11 ms (per MIL-STD810E Method 516.4 Proc 1)
Temperature Range	-20 °C to +80 °C
Dimensions (L \times Ø)	194 × 32 mm

INPUT/OUTPUT SPECIFICATIONS			
Model	Output Type	Input	Output
3400H-1, 3400S-1, 3400SV-1	Millivolt	10 VDC regulated	100 mV (10 mV/V)
3400H-2, 3400S-2, 3400SV-2	Voltage	6.5-35 VDC	0-5 VDC
3400H-3, 3400S-3, 3400SV-3	Current	24 VDC (7–35 VDC)	4–20 mA (2 wire)

CABLE SPECIFICATIONS	
3400H-1, 3400S-1, 3400H-2, 3400S-2	04-375V9: 4 twisted pairs, Violet PVC Jacket, 9.53 mm Ø
3400SV-1, 3400SV-2	04-375VT1: 4 twisted pairs, Black PVC Jacket, integral vent tube, 9.5 mm Ø, transitions to: 04-375V9: 4 twisted pairs, Violet PVC Jacket, 9.5 mm Ø
3400H-3, 3400S-3	02-250V6: 2 twisted pairs, Blue PVC Jacket, 6.35 mm Ø
3400SV-3	02-335VT8 : 2 twisted pairs, Yellow Polyurethane Jacket, integral vent tube, 8.51 mm Ø, transitions to: 02-250V6 : 2 twisted pairs, Blue PVC Jacket, 6.35 mm Ø





